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Bib Data Sheet

CONFIRMATION NO. 8431

<b>SERIAL NUMBER</b> 09/934,474	<b>FILING DATE</b> 08/23/2001 <b>RULE</b>	<b>CLASS</b> 451	<b>GROUP ART UNIT</b> 3723	<b>ATTORNEY DOCKET NO.</b> 50090-334
<b>APPLICANTS</b> Masanobu Iwasaki, Tokyo, JAPAN; Yoshio Hayashide, Tokyo, JAPAN;				
<b>** CONTINUING DATA *****</b>				
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2000-363478 11/29/2000				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 09/27/2001</b>				
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged	Examiner's Signature <i>[Signature]</i> Initials	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 7	<b>TOTAL CLAIMS</b> 20
<b>INDEPENDENT CLAIMS</b> 2				
<b>ADDRESS</b> McDermott, Will & Emery 600 13th Street, N.W. Washington, DC 20005-3096				
<b>TITLE</b> Polishing solution supply system, method of supplying polishing solution, apparatus for and method of polishing semiconductor substrate and method of manufacturing semiconductor device				
<b>FILING FEE RECEIVED</b> 710	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	